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Thin Film Heat Flux Sensor of Improved Design

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ABSTRACT

A new design for a thin film heat flux sensor is presented. It is easier to fabricate than previous designs, for a given heat flux has an order of magnitude larger signal, and is more easily scalable than previous designs. Transient and steady state data are also presented.

INTRODUCTION

Heat flux is one of a number of parameters, together with pressure, temperature, flow, etc., of interest to engine designers and fluid dynamicists. There are various designs of heat flux sensors, such as Gardon gauges (Ref. 1), plug gauges (Ref. 2), and thin film thermocouple arrays (Ref. 3). The thin film types have the advantage of high frequency response and minimal flow disturbance (Ref. 4).

All heat flux sensors operate by measuring the temperature difference across a thermal resistance. Current designs use thermocouples to measure this temperature difference. Because of the small temperature differences involved, and the small output of a single junction, the thermocouples are arranged as a thermopile (Fig. 1). This raises the output by a factor of 30 to 100, depending on the number of junctions in the array. Nevertheless, the signal level is still low, typically a few $\mu\text{V}/(\text{Watt}/\text{cm}^2)$. In addition, the precise alignment required to place each thermocouple element correctly makes fabrication difficult, and restricts the minimum size to about a fourth of an inch in diameter.

Thus we seek a design that retains the advantages of thin films, has a larger output, is easier to fabricate, and can be made smaller.

FABRICATION

The new sensor design consists of a Wheatstone bridge deposited onto a 0.040 in. (1 mm) alumina substrate. Since one is fabricating a resistor array rather than a thermocouple array, this design is much simpler to fabricate than other designs. Alumina is chosen because its thermal conductivity is relatively high (higher than some metals) so that the sensor will not change the thermal resistance and thus distort the measurement. Alumina also has good high temperature properties, and is inexpensive.

The temperature sensitive element is sputter deposited platinum, with line width and line spacing typically a few thousandths of an inch. Platinum also has excellent high temperature properties, and the variation of its electrical resistance with temperature is well characterized. The alumina is washed with soap and DI water, solvent cleaned, dried, and then the pattern applied using a

newly developed photolithography technique. On the single sided gauges, approximately 5µm of silicon dioxide is sputtered over diagonally opposite arms of the bridge.

DESCRIPTION, PRINCIPLE OF OPERATION

Several variations of the new heat flux sensor are shown in figures 2 and 3, in both single sided and double-sided designs. In all cases, the sensor consists of a four active arm Wheatstone bridge, two arms of which are covered by an extra thermal resistance. In the two-sided designs, the substrate upon which the sensor is mounted acts as the extra resistance, and in the one sided designs, the extra resistance is sputtered or electron beam deposited over two of the arms. The bridge itself is made of a material with a high temperature coefficient of resistance, such as platinum or nickel.

With no heat flux applied to the sensor, all of the bridge elements (A, B, C and D in figures 2 and 3) are at the initial temperature T_0 , and have resistance R_0 . With the application of heat flux, the two elements of the bridge not covered by the layer of thermal resistance (B and C) are at a surface temperature designated T_S , and the other two elements under the film of thermal resistance (A and D) are at the temperature $T_F < T_S$. The resistance of the elements are then respectively $R_0[1+\beta(T_S-T_0)]$ and $R_0[1+\beta(T_F-T_0)]$, where β is the linear temperature coefficient of resistance.

If the bridge excitation is V volts, the output from one arm is

$$V_2 = V \frac{R_0 [1 + \beta(T_S - T_0)]}{R_0 [1 + \beta(T_S - T_0)] + R_0 [1 + \beta(T_F - T_0)]}$$

and from the other arm is

$$V_1 = V \frac{R_0 [1 + \beta(T_F - T_0)]}{R_0 [1 + \beta(T_S - T_0)] + R_0 [1 + \beta(T_F - T_0)]}$$

Notice that, R_0 , the initial value of the resistance, cancels.

The instantaneous output from the sensor is then

$$V_{SIG} = V_2 - V_1 = V \frac{\beta(T_S - T_F)}{2 + \beta[(T_F - T_0) + (T_S - T_0)]}$$

Modeling the gauge then consists of calculating the values of T_F and T_S and relating them to the incident heat flux.

STEADY STATE RESPONSE

The gauge is modeled as one-dimensional heat transfer into a two-layer composite as shown in figure 4. The gauge, of thickness l , is mounted on a heat sink, of thickness L . The interface between the layers is at $x = 0$, the surface exposed to the heat flux Q is at $x = -l$, and the base of the substrate is at $x = L$. In the region $-l < x < 0$, the temperature is $T_1(x)$, and the thermal conductivity is k_1 . In the

region $0 < x < L$, the temperature is $T_2(x)$, and the thermal conductivity is k_2 . The temperatures T_1 and T_2 satisfy the steady state heat equation $\frac{d^2 T}{dx^2} = 0$, and satisfy the boundary conditions

$$-k_1 \frac{dT_1}{dx}(x = -l) = Q$$

$$T_1(0) = T_2(0)$$

$$k_1 \frac{dT_1}{dx}(0) = k_2 \frac{dT_2}{dx}(0)$$

$$T_2(x = L) = T_0$$

The solution is $T_1(x) = -Q \frac{x}{k_1} + Q \frac{L}{k_2} + T_0$, $T_2(x) = Q \frac{(L-x)}{k_2} + T_0$, so that

$T_s = T_1(x = -l) = Q \left(\frac{l}{k_1} + \frac{L}{k_2} \right) + T_0$, $T_F = T(0) = Q \frac{L}{k_2} + T_0$, $T_s - T_F = Q \frac{l}{k_1}$, and for steady state heat flux, the sensor output is

$$V_{SIG} = \frac{v\beta Q \frac{l}{k_1}}{2 + \beta Q \left(\frac{l}{k_1} + 2 \frac{L}{k_2} \right)}$$

Typically, for the two sided gauge,

$$l = 0.040'' = 1.016 \times 10^{-3} \text{ m}$$

$$L = 1'' = 2.54 \times 10^{-2} \text{ m}$$

$$k_1 = 36 \text{ W/m/K (Al}_2\text{O}_3)$$

$$k_2 = 15 \text{ W/m/K (type 304 stainless)}$$

$$\beta = 3.98 \times 10^{-3} \text{ K}^{-1} \text{ (Pt)}$$

With a bridge excitation V of one volt and a heat flux Q of $1 \text{ W/cm}^2 = 10^4 \text{ W/m}^2$,

$$V_{SIG} = \frac{1.13 \times 10^{-3}}{2.137} = 528 \text{ } (\mu\text{V/V})/(\text{W/cm}^2)$$

For the one sided gauge, one would typically sputter approximately $5 \mu\text{m SiO}_2$ ($k_1 = 1.4 \text{ W/m/K}$) over the appropriate arms of the bridge. In this case, the output is approximately $68 \text{ } (\mu\text{V/V})/(\text{W/cm}^2)$. These outputs compare favorably with values for commercial gauges, $150 \text{ } \mu\text{V}/(\text{W/cm}^2)$ and $8 \text{ } \mu\text{V}/(\text{W/cm}^2)$ for high temperature gauges.

TRANSIENT RESPONSE

In many applications, the transient response of the gauge is of interest. For time varying heat flux, or while the gauge is coming to equilibrium, it is necessary to find T_S and T_F as functions of time. The temperatures in each layer, the gauge and the substrate, satisfy the heat equation

$$\rho c \frac{\partial T}{\partial t} = k \frac{\partial^2 T}{\partial x^2},$$

where ρ = mass density, kg/m³
 c = specific heat, J/kg/K
and k = thermal conductivity, W/m/K.

For a semi-infinite plane initially at temperature T_0 , with a constant heat flux Q into the surface at $x = 0$, starting at $t = 0$, the temperature as a function of x and t is

$$T(x, t) - T_0 = \frac{2Q}{k} \sqrt{\frac{\alpha t}{\pi}} e^{-\frac{x^2}{4\alpha t}} - \frac{Qx}{k} \operatorname{erfc}\left(\frac{x}{2\sqrt{\alpha t}}\right)$$

where $\alpha = \frac{k}{\rho c}$ is the thermal diffusivity, m²/s,

and $\operatorname{erfc}(x) = 1 - \operatorname{erf}(x) = 1 - \frac{2}{\sqrt{\pi}} \int_0^x e^{-t^2} dt$ is the complementary error function. Note that $\operatorname{erfc}(0) = 1$, and $\operatorname{erfc}(\infty) = 0$. (Ref. 5)

Laplace Transforms can be used to find solutions in terms of infinite series of error functions for the case of planes of finite thickness and for composite planes, but a more practical approach is to solve the problem numerically. In addition, it is possible to solve such problems as temperature dependant material properties or time varying heat flux.

A one dimensional finite volume technique (Ref. 6) was used to find the surface and film temperatures as function of time and position. At the surface $x = 0$, a constant heat flux is applied starting at $t = 0$, while at the other surface, $x = L$, the temperature is held constant. The model is a layer of either 0.040 in. (1 mm) alumina for the two sided design or 5 μ m SiO₂ for the one sided design, on 1" (25.4 mm) stainless steel. The time variation is calculated fully implicitly. The temperatures T_S and T_F are respectively the calculated surface ($x = 0$) and interface temperatures.

DISCUSSION

As can be seen from figures 5–8, the gauges exhibit first order response, with the double-sided gauge having a time constant of approximately 270 μ sec and the single sided gauge a time constant of roughly 7 μ sec. These correspond to frequency responses (-3dB) of about 589 Hz and 23 kHz, respectively. The response of the single sided gauge is comparable to that of the fastest commercial gauges, with advertised time constants of 6 \pm 2 μ sec.

Although testing the sensors in relevant environments is planned, experimentally verifying these numbers is problematical. As it is difficult to produce a step change in heat flux, it may be necessary to use the procedure used in ref. 4 to measure frequency response, that is, to chop the beam from a high power laser to produce a square wave input to the gauge, measure the rate at which the harmonics of the output signal decay with frequency, and compare the decay rate with that of an ideal system with an infinite frequency response. A thermopile design that should have dynamics similar to our single sided design showed a frequency response of only a few kHz. This may be because the insulator used in the thermopile design was nearly transparent to the laser light, lessening the temperature difference, and producing a “droopy” square wave and lower amplitude harmonics. The large amount of metal in the thermopile also reduces the temperature difference. It may also be possible to test gauge response by using a shock tube, but the heat transfer coefficient is unknown. At this point, numerical simulation may be the best option, at least for comparing designs.

CONCLUSION

We have described in this paper a thin film heat flux sensor that is simpler to fabricate than previous gauges, has higher output, and excellent transient response.

Construction of the double sided and single sided designs is ongoing, and in the near future we will be able to compare the predicted and actual gauge outputs.

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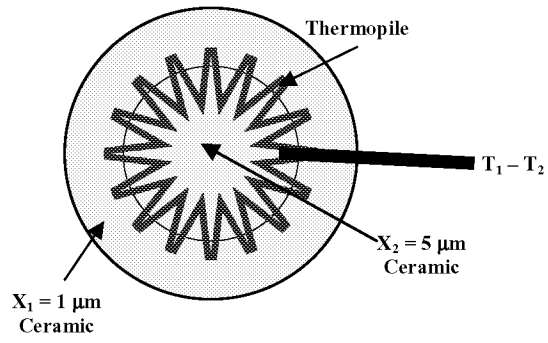


Figure 1: Thermopile-Based Thin Film Heat Flux Sensor (Heat Flux is into the picture).

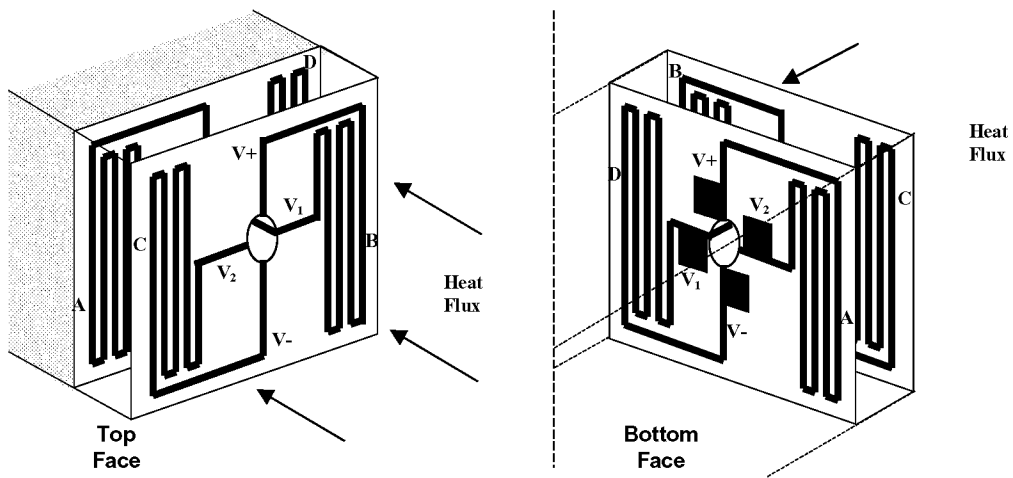


Figure 2: Double-Sided Thin Film Wheatstone Bridge Heat Flux Sensor.

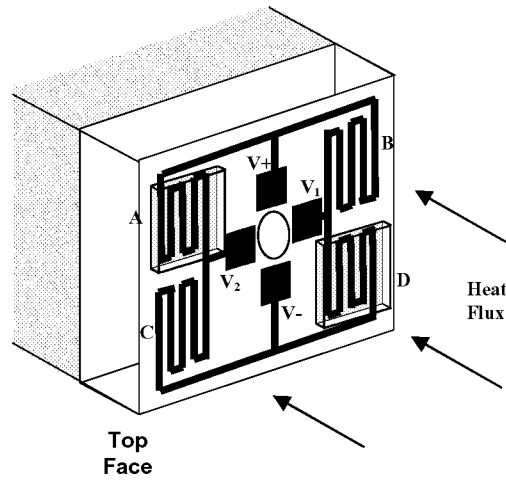


Figure 3: Single-Sided Thin Film Wheatstone Bridge Heat Flux Sensor.

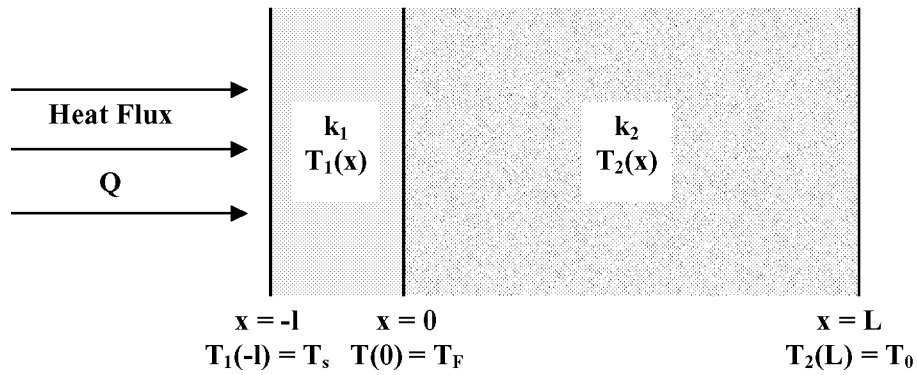


Figure 4: Schematic of One-Dimensional Heat Transfer into a Two-Layer Composite.

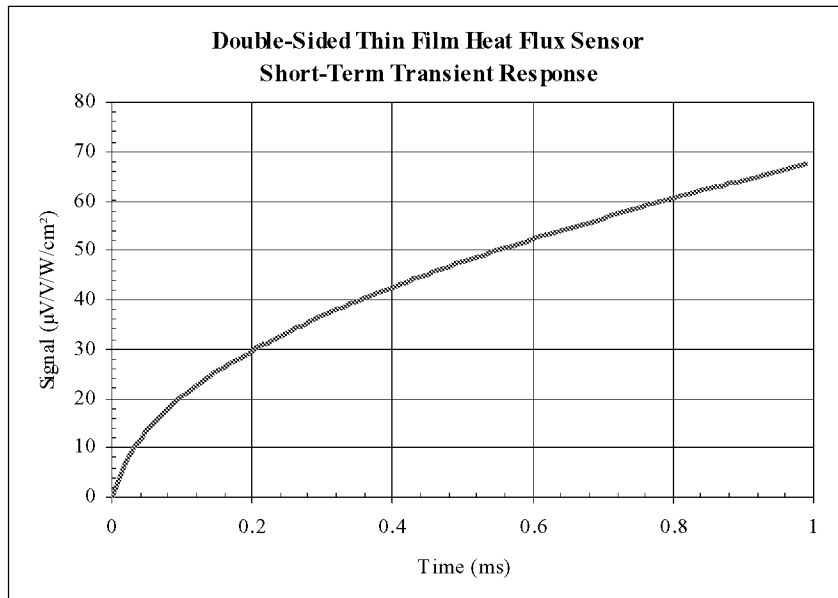


Figure 5: Modeled Short-Term Response for a Double-Sided Wheatstone Bridge Heat Flux Sensor.

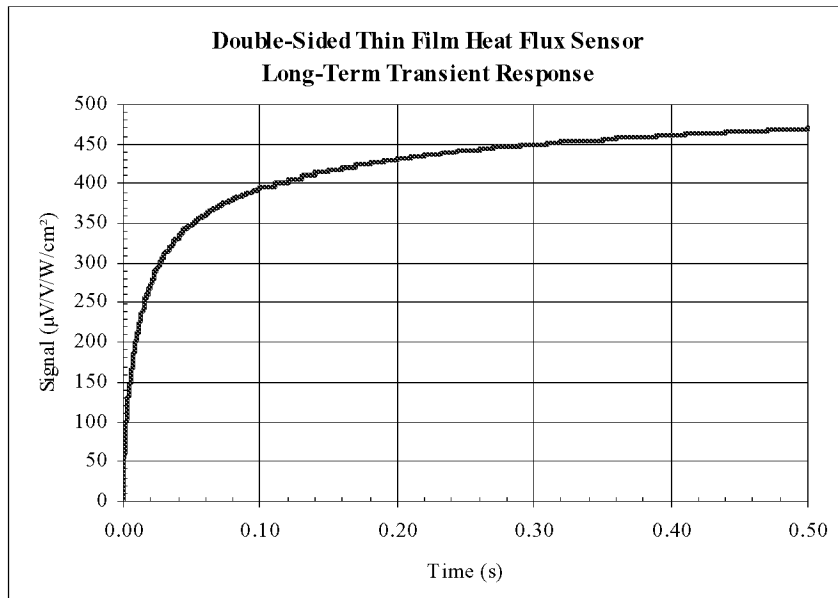


Figure 6: Modeled Long-Term Response for a Double-Sided Wheatstone Bridge Heat Flux Sensor.

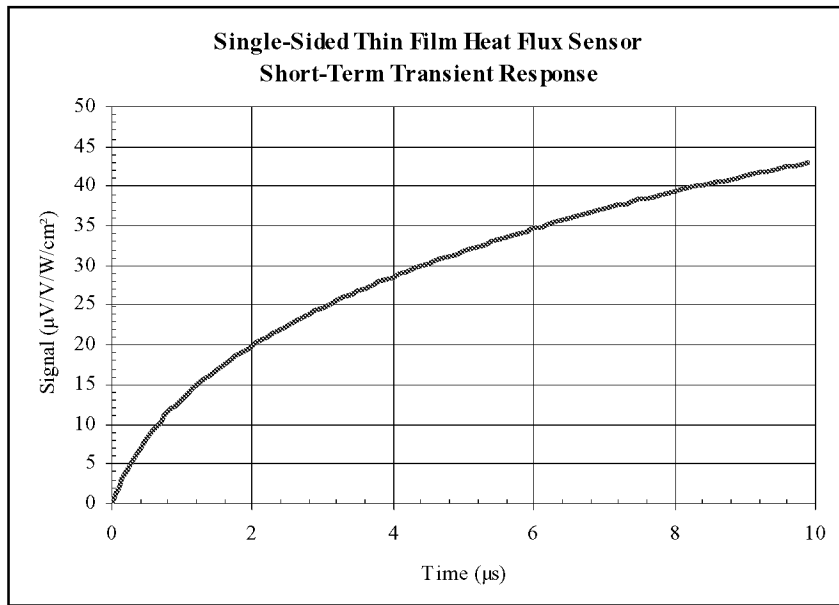


Figure 7: Modeled Short-Term Response for a Single-Sided Wheatstone Bridge Heat Flux Sensor.

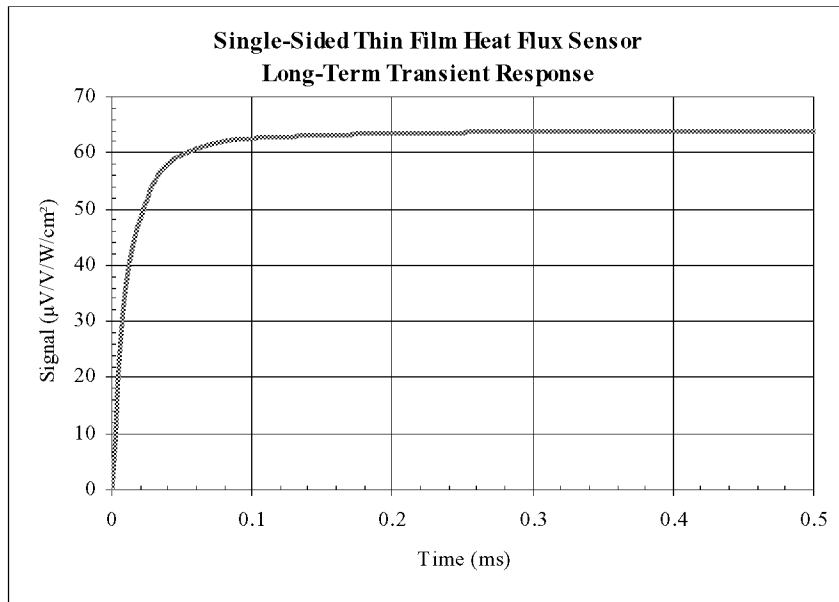


Figure 8: Modeled Long-Term Response for a Single-Sided Wheatstone Bridge Heat Flux Sensor.

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